

# Heating effects and electron-phonon interaction in a two-dimensional hole gas

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A study was made of the effects of heating of two-dimensional holes near the (100), (110), and (111) surfaces of silicon by measuring the anomalous magnetoresistance. An investigation was made of the energy relaxation time of holes  $\tau_\epsilon$ , scattered by phonons, as a function of the lattice temperature and of the carrier density. The observed features of the heating effects were attributed to filling of the second quantum subband.

## 1. INTRODUCTION

The electron-phonon interaction in two-dimensional systems near the surface of a semiconductor has been investigated intensively for over a decade not only because of the fundamental nature and importance of this type of interaction, but also because it is not yet fully understood.<sup>1</sup> One of the methods for investigating this interaction involves a study of the effects of carrier heating by a longitudinal electric field applied along the surface of a semiconductor. The published heating experiments have been devoted mostly to a two-dimensional (2D) electron gas.<sup>2–8</sup> Much less work has been done on a 2D hole gas, although studies of the heating effects and, consequently, of the interaction of phonons in the hole system are undoubtedly desirable because the energy spectrum of 2D holes has a number of special features. In particular, a situation when two size-quantization subbands are filled simultaneously is frequently encountered<sup>1</sup> in the hole subsystem and this may affect the nature of the electron-phonon interaction. The published literature on the heating effects in hole inversion channels is limited to two reports,<sup>3,9</sup> but because of the poor quality of the samples and the complexity of the method employed (involving the use of quantizing magnetic fields up to 100 kG) the information on the interaction of 2D holes with phonons obtained in this way is fragmented and incomplete.

A new impetus for these investigations was provided by the discovery of an anomalous magnetoresistance (AMR)<sup>10,11</sup> which has now become an effective method for investigating electron processes in disordered Fermi systems.<sup>12</sup> It is known that the AMR amplitude obtained in the presence of a fixed magnetic field is determined by the relaxation time  $\tau_\varphi$  of the wave-function phase.<sup>10,13</sup> There have been many investigations (see Ref. 12) of the AMR of 2D

electron systems and it has been found that the relaxation time  $\tau_\varphi$  is determined by inelastic collisions of carriers with one another and is governed by the temperature of the 2D gas. Therefore, the relaxation time  $\tau_\varphi$  and, consequently, the AMR provide a measure of the electron temperature and changes in these quantities can be used to determine this temperature. An important advantage of this method for the determination of the electron temperature, compared with traditional measurements of the amplitude of the Shubnikov-de Haas oscillations, in heating electric fields is the use of weaker magnetic fields, which in contrast to the quantizing fields, do not affect the energy spectrum of carriers and, consequently, do not alter the electron-phonon interaction.

We compared the temperature and field dependences of the AMR to find the temperature of 2D holes at the surface of silicon as a function of the applied electric field. This was used to find the energy relaxation time of holes when they were scattered by phonons. Certain special features of the heating effects due to the filling of two quantum subbands were observed.

## 2. DETERMINATION OF THE TEMPERATURE OF 2D HOLES FROM THE ANOMALOUS MAGNETORESISTANCE CHARACTERISTICS DURING HEATING IN AN ELECTRIC FIELD

We determined the magnetoconductance  $\Delta G(H) = G(H) - G(0)$  of inversion *p*-type channels in magnetic fields *H* up to 3 kG at temperatures in the range 1.6–4.2 K using longitudinal electric fields  $E_{SD}$  up to 5 V/cm. The measurement method was described earlier.<sup>14,15</sup> Nonlinear effects of nonthermal origin, which could affect the conductance and the results of our measurements, were exhibited in our samples only at low hole densities *p*,

TABLE I. Parameters of investigated samples.

Group No.	Orientation	$N_{D,A}$ , $10^{15} \text{ cm}^{-3}$	$\mu$ , $\text{cm}^2$ $\cdot \text{V}^{-1} \cdot \text{sec}^{-1}$	$L$ , $\mu$	$L/W$	$d$ , $\text{\AA}$
1	(100)	0.2	1500	1200	3	1500
2	(100)	1	800	750	3	1200
3*	(100)	5	1500	1800	3.6	1000
4	(111)	0.5	1100	1200	3	1300
5	(111)	0.1	1400	1200	3	1650
6	(110)	0.25	2500	1200	3	1400

Note. Here,  $N_{D,A}$  are the donor and acceptor dopant concentrations;  $\mu$  is the maximum mobility of holes in a channel at 4.2 K;  $L$  and  $W$  are the length and width of the channel;  $d$  is the thickness of the oxide.

\*This denotes inversion channels in MIS-SOS structures.

$\lesssim 7 \times 10^{11} \text{ cm}^{-2}$ . The measurements were carried out in the range of densities  $(1.5\text{--}6) \times 10^{12} \text{ cm}^{-2}$ . Possible contact effects were avoided by the use of potentiometric probes. The parameters and orientation of the surface of the investigated samples are given in Table I. It should be pointed out that the results obtained for samples with different and identical parameters were practically the same provided the orientation of the surface was the same, irrespective of the technology used in the fabrication of the samples, apart from the structures of silicon on sapphire, which will be discussed separately. It had been established earlier<sup>15</sup> that the AMR of a 2D hole gas in silicon was positive for all the main orientations of the surface and could be described fully by a theory of quantum corrections to the conductance subject to an allowance for the spin-orbit interaction.<sup>10</sup> In this case, we can use

$$\Delta G(H) = -\frac{e^2}{2\pi^2 h} \left[ -\frac{3}{2} j(x^*) + \frac{1}{2} j(x) \right], \quad (1)$$

where

$$x = \frac{4DeH}{\hbar c} \tau_q, \quad x^* = \frac{4DeH}{\hbar c} \tau_q^*;$$

$$(\tau_q^*)^{-1} = \tau_q^{-1} + \frac{1}{3} \tau_{so}^{-1}, \quad j(x) = \ln x + \psi(1/2 + 1/x);$$

$\psi(y)$  is the logarithmic derivative of the gamma function;  $D$  is the diffusion coefficient;  $\tau_{so}$  is the spin relaxation time. It was found that the spin relaxation mechanisms were the scattering due to lifting of the spin degeneracy in a noncentrosymmetric system and, in the case of filling of two quantum subbands, the scattering between the heavy- and light-hole bands. Relaxation of the wave-function phase was determined by inelastic collisions of holes with one another subject to an allowance for their scattering on static defects. The temperature dependence of  $\Delta G(H)$  was governed by the dependence of the relaxation time  $\tau_\varphi$  on  $T_L$ , since  $\tau_{so}$  did not vary with temperature.

By way of example, we shall consider now the dependence of the magnetoconductance on the applied magnetic field in the presence of a small longitudinal current when the lattice temperature  $T_L$  was varied (Fig. 1a) and also at a fixed lattice temperature but for different values of the field  $E_{SD}$  (Fig. 1b) applied to one of the samples of the fourth group with the (111) surface orientation. Clearly,  $|\Delta G(H)|$  increased on reduction in temperature and in the longitudinal electric field. We also included in this figure the dependences  $\Delta G(H)$  calculated from Eq. (1) employing the parameters given in the caption of this figure. In all cases the theoretical curves agreed well with the experimental results and an increase in  $|\Delta G(H)|$  as a result of cooling was due to an increase in  $\tau_\varphi$ , similar to that reported in Ref. 15. The values of  $\tau_\varphi$  and  $\tau_{so}$  obtained for different longitudinal electric fields could also be deduced from a comparison of the corresponding experimental and theoretical curves. This comparison indicated that the agreement between the theoretical and experimental dependences remained good on increase in  $E_{SD}$ ; this reduced  $\tau_\varphi$ , whereas the time  $\tau_{so}$  remained unchanged. This behavior of the AMR was explained by the heating of a hole 2D gas in a longitudinal electric field. The power transferred to the hole subsystem increased the energy of thermal motion of carriers; it was then transferred to the lattice by the electron-phonon interaction. A temperature  $T_h$  exceeding the lattice temperature

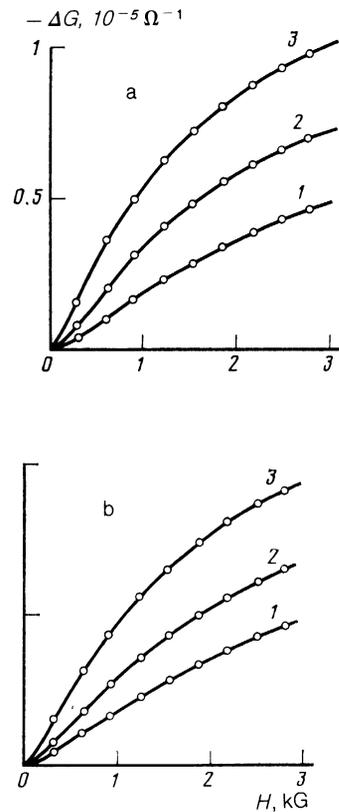


FIG. 1. Dependences of the magnetoconductance  $\Delta G$  of an inversion channel on the (111) surface of Si (sample belonging to group No. 4) on the magnetic field ( $p_i = 3.8 \times 10^{12} \text{ cm}^{-2}$ ,  $D = 11.6 \text{ cm}^2/\text{sec}$ ). a)  $T_L$  (K): 1) 4.2, 2) 2.8, 3) 1.9;  $E_{SD} = 0.18 \text{ V/cm}$ . b)  $E_{SD}$  (V/cm): 1) 5.2, 2) 2.1, 3) 0.75;  $T_L = 1.7 \text{ K}$ . The points are the experimental results and the continuous curves are calculated using Eq. (1) employing the parameters  $\tau_{so} = 0.65 \times 10^{-12} \text{ sec}$  and assuming that: a)  $\tau_\varphi = 5.6, 9.7,$  and  $16.7 \times 10^{-12} \text{ sec}$  (curves 1, 2, and 3, respectively); b)  $\tau_\varphi = 5.6, 7.5,$  and  $14.4 \times 10^{-12} \text{ sec}$  (curves 1, 2, and 3, respectively).

was established inside the hole subsystem, because the electron-electron collision time  $\tau_{ee} \propto \tau_\varphi$  was much less than the energy relaxation time  $\tau_\epsilon$  governed by the scattering on phonons. It should be pointed out that the heating of the lattice subsystem was negligible (it is estimated that it amounted to  $\Delta T_L \approx 1.01 \text{ K}$  when  $\Delta T_h = T_h - T_L \approx 1 \text{ K}$ ). An increase in  $T_h$  increased the frequency of collisions of holes with one another and this reduced  $\tau_\varphi$  and, consequently, also  $|\Delta G(H)|$ , as confirmed experimentally. A comparison of the temperature and field dependences of  $\Delta G(H)$  (Fig. 1) yielded the temperature of the hole subsystem for different values of the power  $P = GE_{SD}^2$  delivered by the electric field to the system. Figure 2 shows the  $T_h(P)$  dependence obtained for samples with the (111) and (100) orientations. Clearly, up to  $P = 5 \times 10^{-5} \text{ W/cm}^2$  the temperature  $T_h$  of 2D holes at the (111) surface was not affected significantly and then it began to rise in accordance with the law  $(T_h^5 - T_L^5) \propto P$ . For 2D holes at the (100) surface the heating began (Fig. 2) at higher pump powers, although the mobility, effective masses, and carrier densities were practically the same for these orientations.

The heating effects were also investigated in the case of 2D holes in channels of metal-insulator-semiconductor (MIS) transistors made from silicon-on-sapphire (SOS)

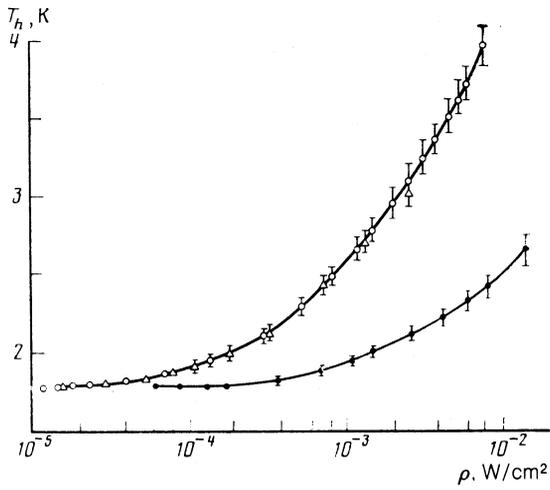


FIG. 2. Dependences of the temperature of a two-dimensional hole gas on the pump power ( $T_L = 1.7$  K). Samples belonging to different groups: ○) No. 4, ●) No. 1; △) No. 3;  $p_s = 3.6 \times 10^{12} \text{ cm}^{-2}$ .

films when the Si orientation was (100); a special feature of transistor structures was a compressive strain which increased the energy gap between the light- and heavy-hole subbands. Before beginning our analysis of the dependences of  $\Delta G(H)$  on  $T_L$  and  $E_{SD}$  in the case of MIS-SOS structures, we shall discuss some characteristics of the AMR in this case. It had been established<sup>14,15</sup> that the AMR of these structures had a variable sign, in contrast to inversion channels in undeformed silicon when the AMR was always positive. It was found that when the AMR was positive (in the range of magnetic fields used in these experiments), the inequality  $\tau_\varphi > \tau_{so}$  was satisfied, but cooling (i.e., reduction of  $\tau_\varphi$ ) reversed this inequality and this reversed the sign of the magnetoresistance. Application of heating electric fields also increased the temperature of the system. Therefore, in low longitudinal electric fields the values of  $\Delta G(H)$  were negative, but on increase in  $E_{SD}$  the sign of the magnetoresistance was reversed. This is illustrated in Fig. 3, which gives the dependences  $\Delta G(H)$  for an MIS-SOS structure subjected to different longitudinal electric fields. Clearly, an increase in  $E_{SD}$  reversed the sign of the magnetoconductance from negative to positive and the theoretical curves agreed well with the experimental results for the values of  $\tau_\varphi$  and  $\tau_{so}$  given above. An increase in  $E_{SD}$  did not affect the value of  $\tau_{so}$ , but it reduced  $\tau_\varphi$ , corresponding to an increase in the temperature of 2D holes. A comparison of the temperature and field dependences of the AMR yielded the dependence of the temperature of the hole subsystem on the pump power, shown in Fig. 2. This dependence was clearly identical with the dependence  $T_h(P)$  for 2D holes at the (111) surface.

### 3. ENERGY RELAXATION TIME OF 2D HOLES SCATTERED BY PHONONS

Heating in an electric field is characterized by an energy relaxation time  $\tau_\epsilon$  determined from the balance of the energy received by carriers from the field and of the energy transferred from the carriers to the phonon subsystem on condition that  $\Delta T_h \ll T_L$  (Ref. 16):

$$P = C(T) (T_h - T_L) / \tau_\epsilon = \pi^2 k^2 \bar{T} (T_h - T_L) N / 3 \tau_\epsilon, \quad (2)$$

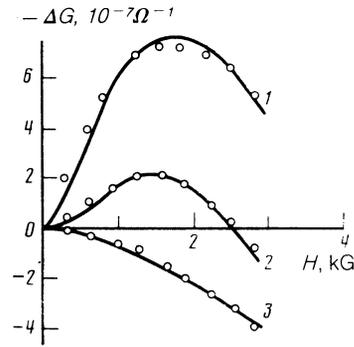


FIG. 3. Dependences of  $\Delta G(H)$  for an inversion channel on the (100) surface of Si in MIS-SOS structures (sample of group No. 3,  $T = 1.7$  K,  $p_s = 1.6 \times 10^{12} \text{ cm}^{-2}$ ,  $D = 5.2 \text{ cm}^2/\text{sec}$ ) obtained in different electric fields  $E_{SD}$  (V/cm): 1) 0.42; 2) 1.62; 3) 7.4. The points are the experimental values and the continuous curves are calculated using Eq. (1) and assuming the following values  $\tau_\varphi$  ( $10^{-12}$  sec): 1) 9.3; 2) 6.3; 3) 1.6;  $\tau_{so} = 6.2 \times 10^{-12}$  sec.

where  $N = m_p^* / \pi \hbar^2$  is the density of states at the Fermi level and  $m_p^*$  is the effective mass of holes, which is equal to the mass of heavy holes  $m_h^*$  in the case of filling of one quantum subband and  $m_p^* = m_h^* + m_l^*$  ( $m_l^*$  is the mass of a light hole) in the case of filling of two quantum subbands. It should be noted that Eq. (2) is valid only in the case of a weak parabolicity of the dispersion law of carriers [ $(dN/d\epsilon)_{\epsilon_F} \epsilon_F \ll N$ ]. This situation is encountered in 2D hole gas in the range of densities  $p_s \gtrsim 1.5 \times 10^{12} \text{ cm}^{-2}$  under consideration.<sup>1</sup>

The initial part of the dependence  $T_h(P)$  and the relationship (2) can be used to find the relaxation time  $\tau_\epsilon$ . In our case this initial region is limited by the condition  $\Delta T_h / T_L \lesssim 15\%$ . The results obtained for all the investigated silicon surface orientations are presented below. Figure 4a gives the dependence  $\tau_\epsilon(p_s)$  for 2D holes near the (111) surface. Clearly,  $\tau_\epsilon$  decreased on increase in  $p_s$  in accordance with a near-linear law. It is clear from Fig. 4b that in the case of the hole 2D gas at the (100) surface the time  $\tau_\epsilon$  behaved differently: in the case of undeformed structures (curve 2) the relaxation time was, firstly, several times smaller than the value of  $\tau_\epsilon$  for holes at the (111) surface and, secondly, it

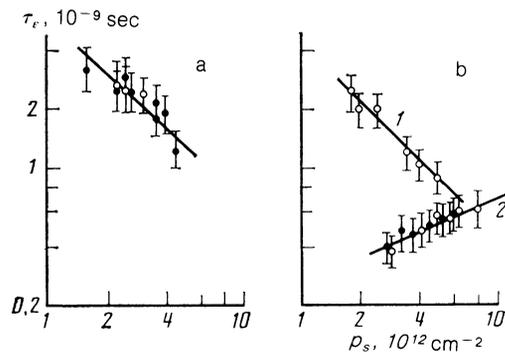


FIG. 4. Dependences of the energy relaxation time  $\tau_\epsilon$  on  $p_s$  for samples with different orientations of the surface ( $T_L = 1.7$  K): a) sample with the (111) orientation (the black points represent group No. 4 and the open circles represent group No. 5); b) sample with the (100) orientation [line 1 represents group No. 3, whereas line 2 represents group No. 1 (black points) or group No. 2 (open circles)].

increased on increase in the density in accordance with the law  $\tau_e \propto p_s^\alpha$ , where  $\alpha = 0.5 \pm 0.4$ . In the case of MIS-SOS structures (curve 1) the behavior of  $\tau_e$  was practically identical with the behavior of the energy relaxation time of holes at the (111) surface. In the case of holes at the (110) surface of Si we determined the value of  $\Delta T_h / P$  because in the case of this system the filling of the second quantum subband began in the range of densities  $p_s = (2-3) \times 10^{12} \text{ cm}^{-2}$ . This did not allow us to determine  $\tau_e$  from Eq. (2), because at the moment of transition there was an abrupt change in the density of states at the Fermi level.

Figure 5 shows the dependence of  $\Delta T_h / P$  on  $p_s$  for holes near the (110) surface. Clearly, in the density range  $(1.5-2.5) \times 10^{12} \text{ cm}^{-2}$  there was first a slight change and then a rapid fall of  $\Delta T_h / P$ , beginning from  $p_s = 2.5 \times 10^{12} \text{ cm}^{-2}$ , which corresponded to the onset of filling of the second quantum subband deduced from the conductance measurements and from the Shubnikov-de Haas oscillations. A further increase in  $p_s$  caused  $\Delta T_h / P$  to pass through a minimum and then it began to rise in the same way as  $\tau_e$  in the case of the (100) surface of undeformed samples.

It therefore follows from these results that the main feature of the energy relaxation time was its strong dependence on the surface orientation and on the presence or absence of deformation.

In addition to the dependences  $\tau_e(p_s)$ , we also determined the dependences of the energy relaxation time of 2D holes on the lattice temperature. Figure 2 shows the dependences  $\tau_e(T_L)$  obtained for samples with the (111) and (100) surface orientations and a density  $p_s = 3.6 \times 10^{12} \text{ cm}^{-2}$ . It is clear from this figure that the experimental dependence obeyed  $\tau_e \propto T^{-p}$ , where  $p = 3.1 \pm 0.5$ , and it was independent of the surface orientation. A similar result was obtained for  $p_s = 2.5 \times 10^{12} \text{ cm}^{-2}$  and the power exponent in this case was  $p = 3.5 \pm 0.5$ .

## 4. DISCUSSION OF RESULTS

### 1. Temperature dependence of the relaxation time $\tau_e$

Two-dimensional carriers in inversion channels may be scattered by surface and bulk (volume) acoustic phonons.<sup>3,8,9,17-19</sup> It was shown in Refs. 8 and 18 that in both cases we have  $\tau_e \propto T_L^{-3}$  and the temperature dependence is insufficient to distinguish one energy relaxation mechanism from the other. However, an analysis of the scattering by surface

phonons shows that this mechanism can be ignored compared with the scattering by bulk phonons if the temperature is sufficiently low.<sup>18,19</sup> The energy relaxation time for the scattering by bulk phonons is described by<sup>18</sup>

$$\tau_e = \frac{\pi^2 k (T_h^2 - T_L^2)}{6 \epsilon_F} \left\langle \frac{d\epsilon}{dt} \right\rangle^{-1},$$

$$\left\langle \frac{d\epsilon}{dt} \right\rangle = \frac{3 \xi(5) (2m)^{1/2} \Xi^2 k^5 T^4}{\pi \rho \hbar^4 s^4 \epsilon_F^{3/2}} \Delta T_h, \quad (3)$$

where  $\Xi$  is the deformation potential constant;  $s$  is the velocity of sound;  $m$  is the electron mass;  $\rho$  is the density of Si. Equation (3) is derived on the assumption that  $q_{ph} \ll 2k_F$ , where  $k_F$  is the Fermi wave vector of an electron and  $q_{ph}$  is the momentum of a phonon corresponding to the maximum of the electron-phonon interaction (in our case, this momentum is  $q_{ph} = 3.9kT/\hbar s$ ); this equation applies also if  $q_{ph} l > 1$ , where  $l$  is the mean free path of an electron measured using its momentum in the case of scattering by impurities. These conditions are satisfied only in few experimental situations. It is reported in Refs. 3, 9, and 9 that  $\tau_e \propto T^{-p}$ , where  $p = 2$  for high-mobility samples ( $\mu = 10^4 \text{ cm}^2 \cdot \text{V}^{-1} \cdot \text{sec}^{-1}$ )<sup>3</sup>,  $p = 3$  for samples with  $\mu = 10^3 \text{ cm}^2 \cdot \text{V}^{-1} \cdot \text{sec}^{-1}$ , and  $p = 3$  for samples with low and high electron mobilities.<sup>8</sup> It has been shown recently<sup>20,21</sup> that in the 2D case the electron-phonon interaction is enhanced when the phonon wave vector becomes comparable with  $2k_F$ . This may give rise to the dependence  $\tau_e \propto T_L^{-2}$  at temperatures such that  $q_{ph} > 2k_F$  and to the dependence  $\tau_e \propto T_L^{-4}$  when  $q_{ph} \lesssim 2k_F$ . In all the investigated experimental situations we have  $q_{ph} \lesssim 2k_F$  in the temperature range  $1.5 \text{ K} < T < 10 \text{ K}$ , so that the correct dependence  $\tau_e(T_L)$  can be found by a more careful analysis, as was done in Refs. 3, 8, and 9. When the density of 2D holes corresponds to the dependence  $\tau_e(T_L)$  shown in Fig. 6, the momentum  $q_{ph}$  becomes comparable with  $2k_F$  at 12 K, i.e., in our case the condition  $q_{ph} \ll 2k_F$  is satisfied quite well. Therefore, the experimentally determined dependence  $\tau_e \propto T^{-p}$ , where  $p = 3.3 \pm 0.7$ , is not in conflict with the theoretical predictions made in Ref. 18 [see Eq. (3)].

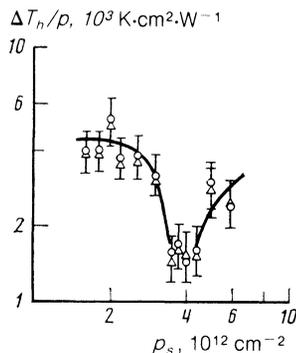


FIG. 5. Dependences of  $\Delta T_h / P$  on  $p_s$  for samples with the (110) orientation (group No. 6): the points correspond to  $\Delta T_h = 0.25 \text{ K}$  and the triangles to  $\Delta T_h = 0.35 \text{ K}$ ;  $T_L = 1.75 \text{ K}$ .

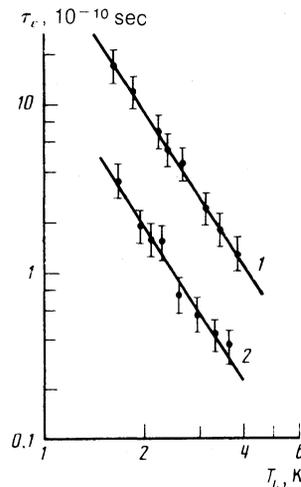


FIG. 6. Dependences of  $\tau_e$  on the lattice temperature  $T_L$  for samples with different orientations of the surface ( $p_s = 3.6 \times 10^{12} \text{ cm}^{-2}$ ): 1) sample of group No. 4, (111) orientation; 2) sample of group No. 1, (100) orientation.

## 2. Dependence of the relaxation time on the density of carriers in a channel

The relationship (3) predicts also an increase in the relaxation time  $\tau_\epsilon$  on increase in  $p_s$  in accordance with the law  $\tau_\epsilon \propto p_s^{1/2}$ . However, we can see from Fig. 4 that in the case of the (111) orientation and also for MIS-SOS structures the relaxation time  $\tau_\epsilon$  decreases on increase in the hole density. Such a dependence is reported in Ref. 8 for an electron 2D gas in low-mobility samples. The reduction in  $\tau_\epsilon$  on increase in  $p_s$  may be due to impurity scattering. It is known that the electron-phonon interaction depends on the ratio of the phonon wave vector to the mean free path of an electron.<sup>22</sup> If  $q_{ph}l < 1$ , an analysis of the electron-phonon interaction<sup>22</sup> shows that the time  $\tau_\epsilon$  becomes proportional to  $T_L^{-4}$  and decreases on increase in the mean free path. In our case we have  $q_{ph}l \approx 1-2.5$  and the contribution of phonons with the wave vectors satisfying  $q_{ph}l < 1$  to the energy relaxation process may be sufficient to influence the dependence  $\tau_\epsilon(p_s)$ . The reduction in  $\tau_\epsilon$  on increase in  $p_s$  may be due to an increase in the mean free path which does indeed increase in the investigated structures on increase in  $p_s$ , but a more detailed analysis of this hypothesis will require a theory allowing for the impurity scattering. Another explanation relates the reduction in  $\tau_\epsilon$  to an increase in the deformation potential constant.<sup>8</sup> However, in this case we can describe the dependence  $\tau_\epsilon(p_s)$  for holes at the (111) surface only if we assume that an increase of  $p_s$  from  $1.5 \times 10^{12}$  to  $5 \times 10^{12}$  cm<sup>-2</sup> increases the deformation potential constant  $\Xi$  from 15 to 35 eV, i.e., it is necessary to assume that the inversion channels are characterized by an anomalously large deformation potential constant.

We shall consider the  $\tau_\epsilon(p_s)$  dependence for holes near the (100) surface of undeformed silicon (Fig. 4b). In this case we observed two features of the behavior of  $\tau_\epsilon$ , different from that of the holes at the (111) and (100) surfaces in the case of MIS-SOS structures: firstly, the value of  $\tau_\epsilon$  was less than in the case of the (111) and (100) orientations in MIS-SOS structures and, secondly,  $\tau_\epsilon$  did not decrease but increase on increase in  $p_s$ . This behavior may be due to filling of two quantum subbands, because when the Fermi level reaches the bottom of a subband, the density of states of 2D carriers increases and new channels of the scattering by phonons appear (these are associated with intersubband transfer). The first and second factors should reduce strongly  $\tau_\epsilon$  as the Fermi level passes to the second quantum subband. However, we do not know the reason for the rise of  $\tau_\epsilon$  on increase in the hole density. This may be due to a reduction in the rate of intersubband transfer induced by phonons.

## 5. CONCLUSIONS

An investigation of the anomalous magnetoresistance of a hole 2D gas at the surface of silicon subjected to heating electric fields provides a simple and effective method for the determination of the temperature of holes when they are heated by an electric field. We used this method to investi-

gate the relaxation time of holes scattered by phonons as a function of the lattice temperature, of the hole density, and of the orientation of the silicon surface, and also in the presence of isotropic deformation. It was established that whereas the dependence of the relaxation time on the lattice temperature was the same for all the investigated samples,  $\tau_\epsilon \propto T_L^{-(3.3 \pm 0.7)}$ , the value of  $\tau_\epsilon$  and its carrier-density dependence were greatly affected by the surface orientation. It was concluded that the orientational dependence of  $\tau_\epsilon$  was associated with the nature of filling of the second quantum subband in samples with the (100) and (111) surface orientations. It was shown that the currently available theory of the electron-phonon interaction in two-dimensional systems fails to provide a complete description of the experimental results obtained in the present study and it is necessary to generalize this theory so as to allow for the impurity scattering and also for intersubband transfer.

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